

OR0505

Cluster tool for in situ processing and characterization of thin films at high temperatures

Matthias Krause¹, Robert Wenisch², Frank Lungwitz¹, Irene Heras³, Ibon Azkona⁴, René Heller¹, René Hübner¹, Johannes von Borany¹, Sibylle Gemming¹, Ramon Escobar-Galindo⁵

¹Helmholtz-Zentrum Dresden-Rossendorf, Dresden, Germany ²PVcomB, Helmholtz-Zentrum Berlin, Berlin, Germany ³University of Salamanca, Salamanca, Spain ⁴Metal Estalki S.L., Zamudio, Spain ⁵Universidad de Cádiz, Puerto Real, Spain

matthias.krause@hzdr.de

In situ processing and comprehensive characterization is essential for design and development of thin films and coatings used in high-temperature applications and processes. Here, a new cluster tool for processing and depth-resolved compositional, structural and optical characterization of layered materials with thicknesses ranging from sub-nm to 1 μm and for temperatures of -100 to 800 $^{\circ}\text{C}$ is described. The implemented techniques comprise magnetron sputtering, ion irradiation, Rutherford backscattering spectrometry, Raman spectroscopy and spectroscopic ellipsometry. The combination of techniques enables sample processing by scalable, clean, waste-free, and industry-relevant technologies, quantitative depth-profiling for elements with $Z \geq 6$, structural and chemical characterization, sensitivity and nm-precise thickness and optical information for single layers, multilayers and mixtures. The performance of the cluster tool is demonstrated for metal-induced crystallization of a model layer stack MgO/ a-Si (~60 nm)/ Ag (~30 nm), and for high-temperature characterization of two solar-selective coating types developed for concentrated solar power applications, namely $\text{Al}_y\text{Ti}_{1-y}(\text{O}_x\text{N}_{1-x})$ -based single and multilayers as well as an n-type doped transparent conductive oxide. Financial support by the EU, grant No. 645725, project FRIENDS², and the HGF via the W3 program (S.G.) is gratefully acknowledged.

Keywords

Thin films
in situ
processing
characterization
high temperatures